TECHNICAL SPEC FOR Stepper 15

System Model:
Canon FPA 2000 i1, SN : 406352i1

Tool has been shut down by Litho tech.
Electricity, cooling water, Vacuum and CCA are closed.
Cables between Main unit and power box are still connected, locking kit and demounting for transport to be provided by buyer.

Wafer size: 6 inch

Wafer type: Jeida flat

Chuck type: pin chuck

Reticle changer type: I1 box 14 reticles, standard

Inline right or left: Left

Particle checker (PPC): NO

Touch panel type: Canon standard

Options: None

Reticle size: 5 inch

Reticle alignment: Reticle rotation repeatability <=0.03 um

Wafer alignment: <=0.15 um

Auto focus: <= 0.15 um

Auto feeder: Yes

Wafer tilt:

Wafer feeder: Yes

Track interface: Yes (stepper was used inline with track, track interface is track part)

Laser: HeNe

Lens data:

Stage and U-lens (current)
- **Intensity: 500 mW/cm2**
- **Distortion: <= 0.07 um**
- **Uniformity: 2 %**

Used for 0.35micron line and space? No

Chuck maintenance tool: No

Reticle bar code reader: Yes

Cassette bar code reader: No

SW Version:

OS:

Vintage:2011

Missing/defective parts: none

Tool acceptance data:

Ventex CORPORATION

CANON STEPPER FPA2000i1 INSTALLATION CHECK

CUSTOMER : On Semi	SYSTEM ID : Stepper 15	S / N : 406352i1
RETICLE # :	WAFER # :	DATE : February 2011

NO	CHECK ITEM		INITIAL	FINAL	SPEC.	√
1	PRESS ROLLER TENSION	XL	4		4 ± 0.5 Kgf	
		XR	4			
		YF	4			
		YB	4			
2	X-Y STAGE LASER POWER : (HP)		458		≥ 200 µW	
	(ZYGO)				≥ 300 µW	
3	X-Y STAGE : (OFFSET) PST – COM	X	0.5	0	0 ± 1 mV	
		Y	-0.3	0		
	(OFFSET) XP - XM	X	120	0	0 ± 10 mV	
	YP - YM	Y	60	0		
	(SPEED) VAJ - COM	X	1.985	1.980	1.975 ± 0.02 KHz	
		Y	1.985	1.975		
	(HIGH GAIN) DA - COM	X	1-1		½ ~ 1 Cycle	
		Y	1-1			
	(LOW GAIN) DA - COM	X	1 ½ -1 ½		2 ± 1 Cycle	
		Y	1 ½ - 2 ½			
4	A/F : (P/A) CCD	X	0.8		0.8 ± 0.2 V	
		L	0.8			
		R	1.0	0.8		

NO	CHECK ITEM		INITIAL	FINAL	SPEC.	√
7	EDDY CURRENT SENSOR VOLTAGE	Z0	97	95.1	95 ± 3 mV	
		Z1	91.7	95.0		
		Z2	92.4	94.9		
		Z3	95.3	95.0		
8	UNIFORMITY		1.8	1.6	≤ 1.2 %	
9	INTENSITY		723	718	≥ 600 mW / cm²	
10	LIRC ACCURACY (OVERALL)		0.294		≤ 1.2 %	
11	FRA MEASUREMENT STABILITY (3 σ) (1/1000th mode)	XL	0.004		≤ 0.01 μm	
		YL	0.002			
		XR	0.004			
		YR	0.002			
12	Z-DRIVE (PIEZO) GAIN	Z0	1.0104	00.9970	1.00 ± 0.01	
13	5-CHANNEL OPAF GAIN	CH1	1.000		1.00 ± 0.01	
		CH2	1.000			
		CH3	1.002			
		CH4	1.006			
		CH5	1.003			
14	TILT-DRIVE (PIEZO) GAIN	Z1	1.0007		1.00 ± 0.01	
		Z2	1.0003			
		Z3	1.0013			
15	GTOC STABILITY (3 σ)	X	3.1		≤ 5 ppm	
		Y	2.6			
16	GTOC REPEATABILITY (3 σ)	X	1.7		≤ 10 ppm	
		Y	2.7			
17	FOCUS & TILT STABILITY (3 σ)	F	0.055		≤ 0.12 μm	
		X	2.240		≤ 10 ppm	
		Y	3.01			
18	FOCUS & TILT REPEATABILITY (3 σ)	F	0.07		≤ 0.15 μm	
		X	3.67		≤ 15 ppm	
		Y	3.80			

Photos to Collect

- All 4 sides

- Loader
- Chuck
- Cameras
- Control panel
- Chamber
- Robot
- Inside all of the cabinets (PCB’s)
- Electronic racks (inside the boards as well)
- All electronic in/outlets
- Serial plate
- Spare parts, manuals (if any)